

GATE simulation

LYSO-200um_Plastic-250um

Scintillator tiles



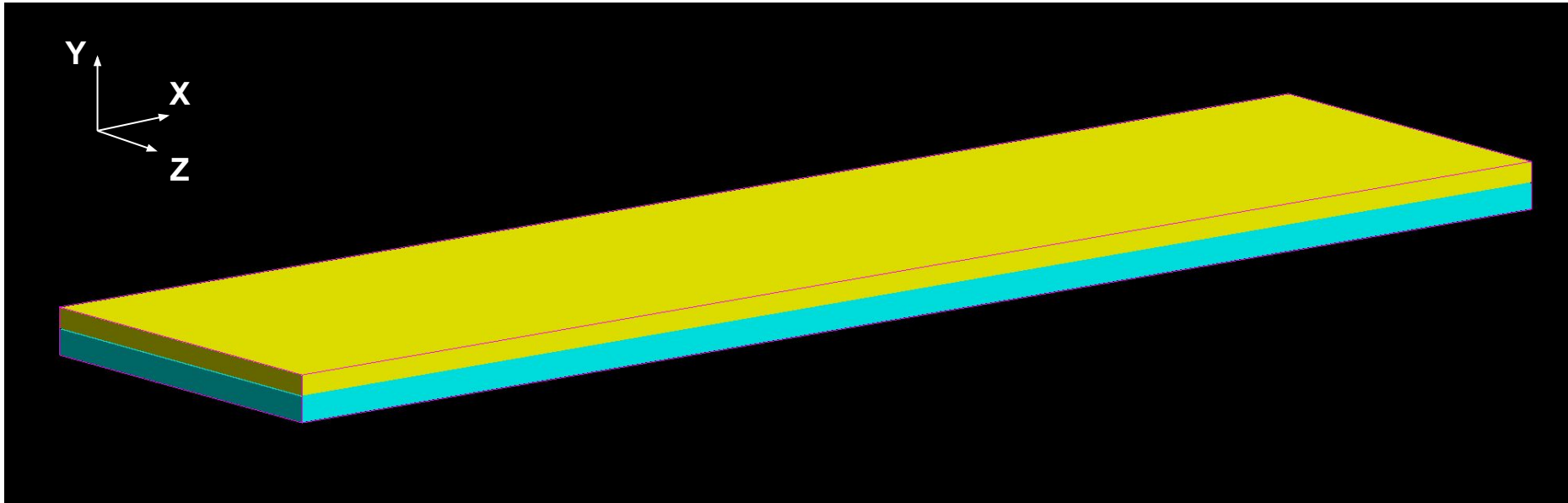
- **LYSO (yellow):**

- 15 mm x 0.20 mm x 3.75 mm
- $d = 7.1 \text{ g/cm}^3$
- GATE “layer 0”

- **Plastic (cyan):**

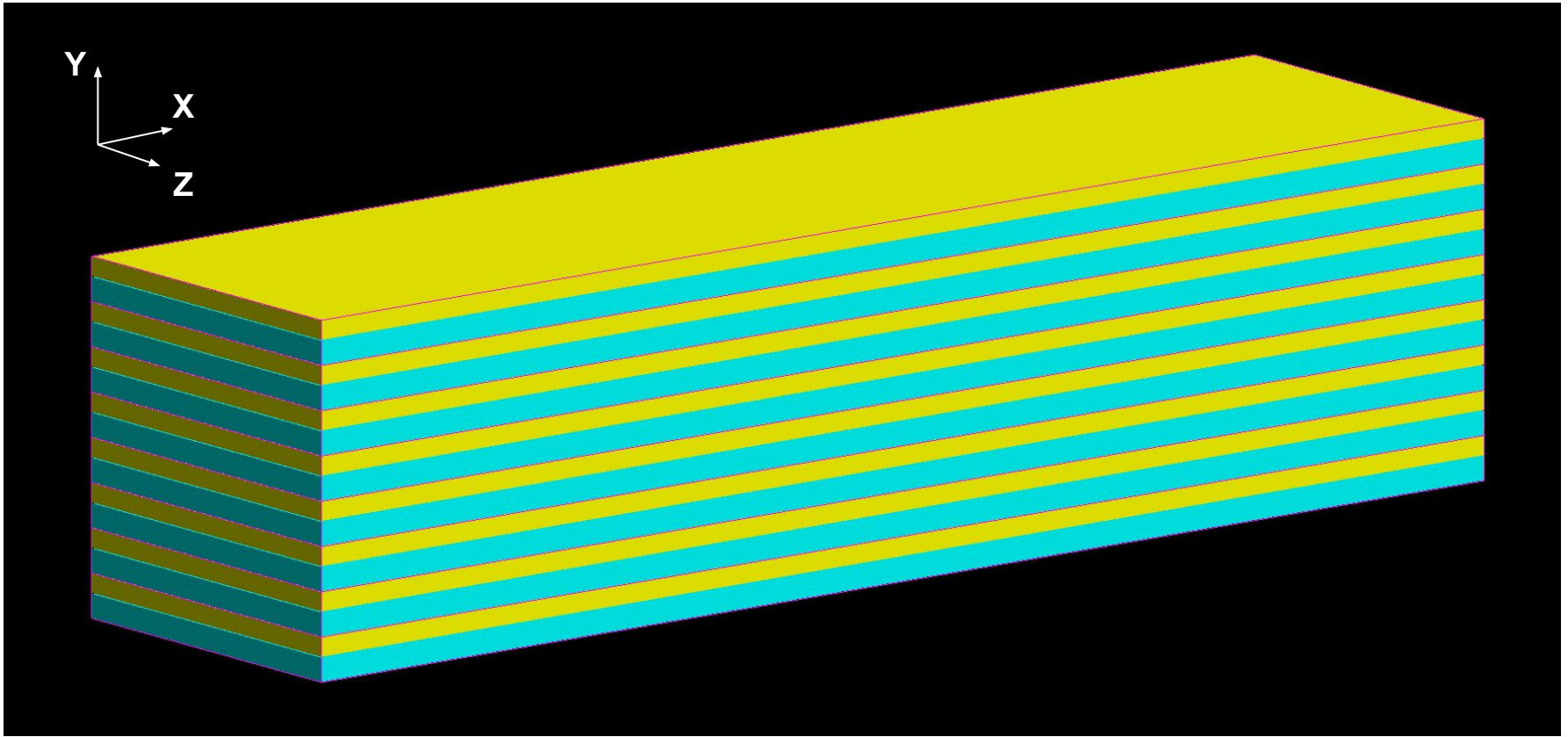
- 15 mm x 0.25 mm x 3.75 mm
- $d = 1.18 \text{ g/cm}^3$
- GATE “layer 1”

Stacking



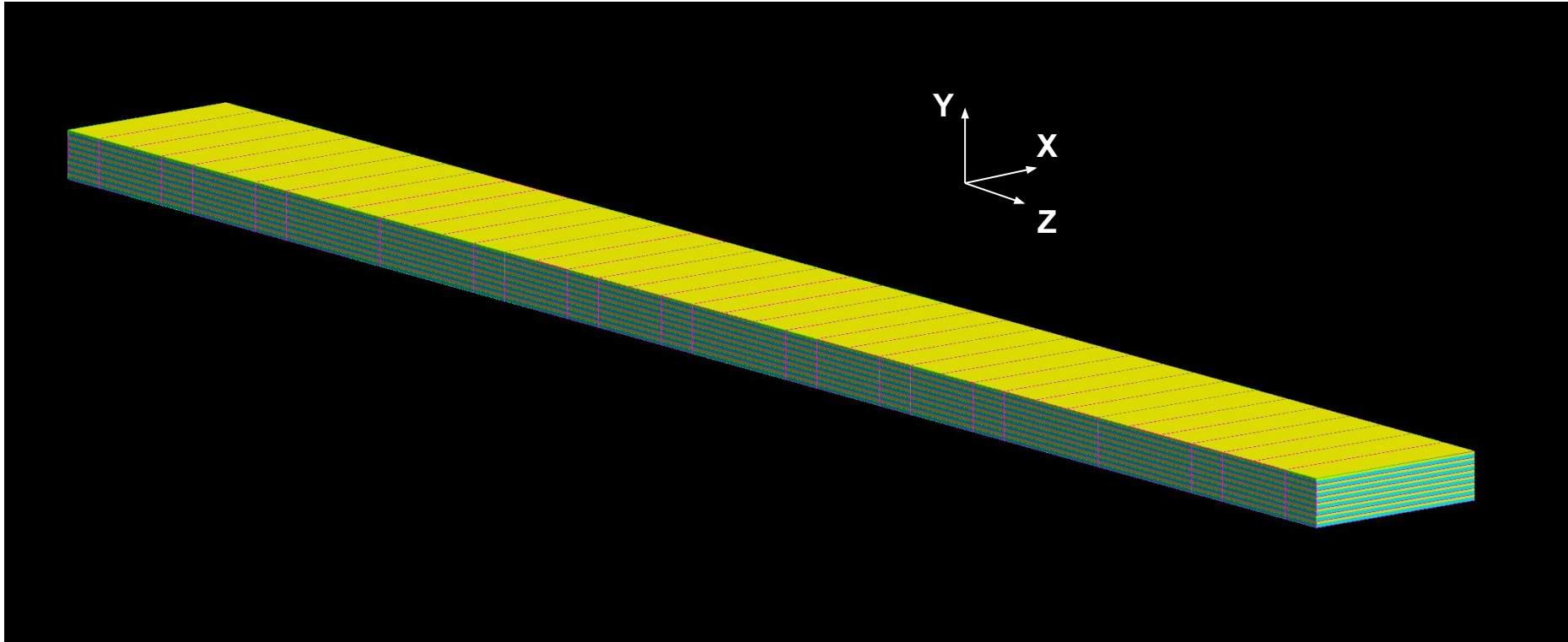
- 1 Plastic and 1 LYSO volume stacked together
 - 10 microns gap (air) between volumes
 - In GATE, these two together define a “crystal” (magenta)

A pixel



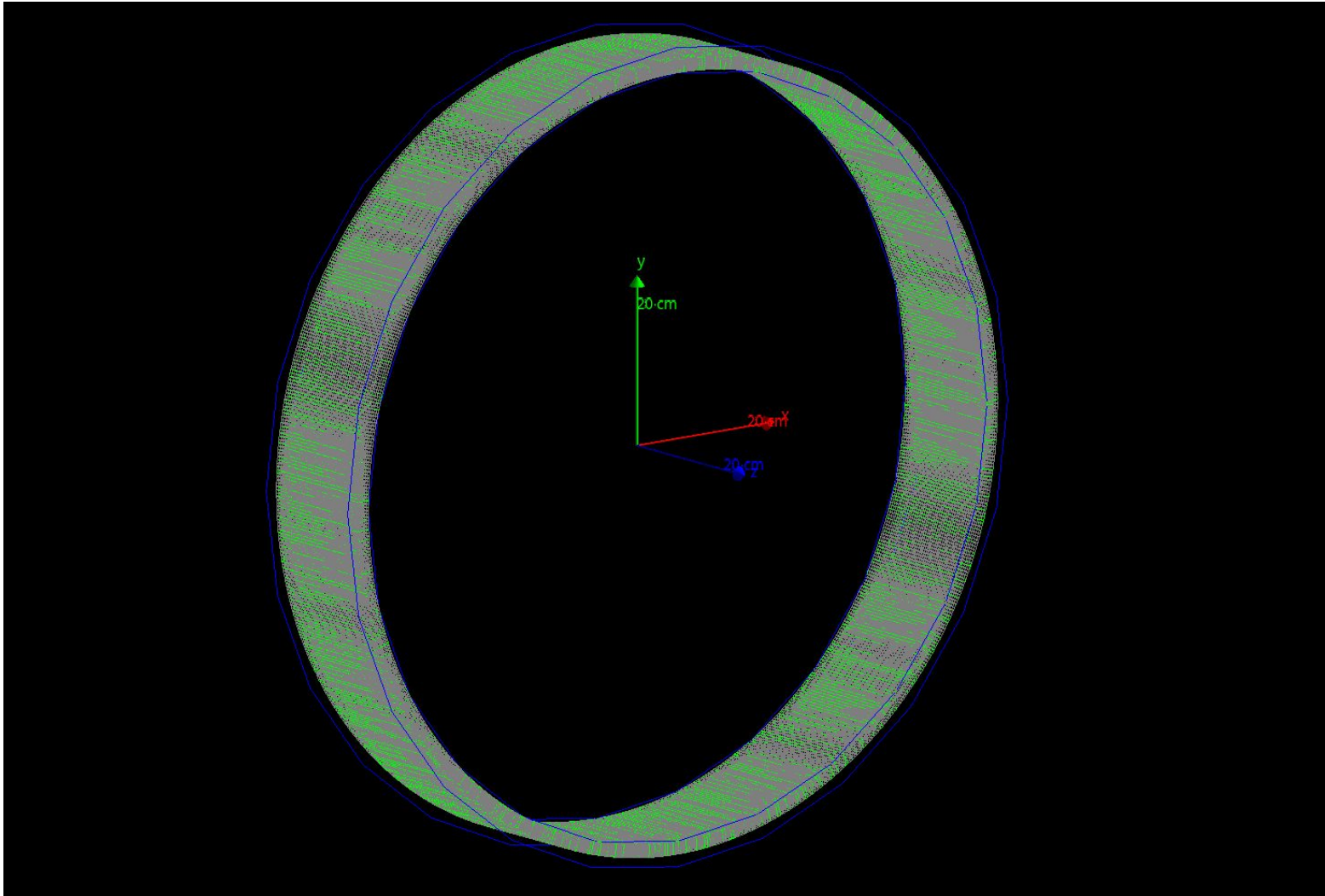
- A repetition of 8 “GATE crystals” in y direction
 - Gap of 10 microns between “GATE crystals”
 - Total volume 15 mm x 3.76 mm x 3.76 mm
 - In GATE, this is a “module”
 - The **digitizer adder** is set to the module depth (setDepth 2)

rsector



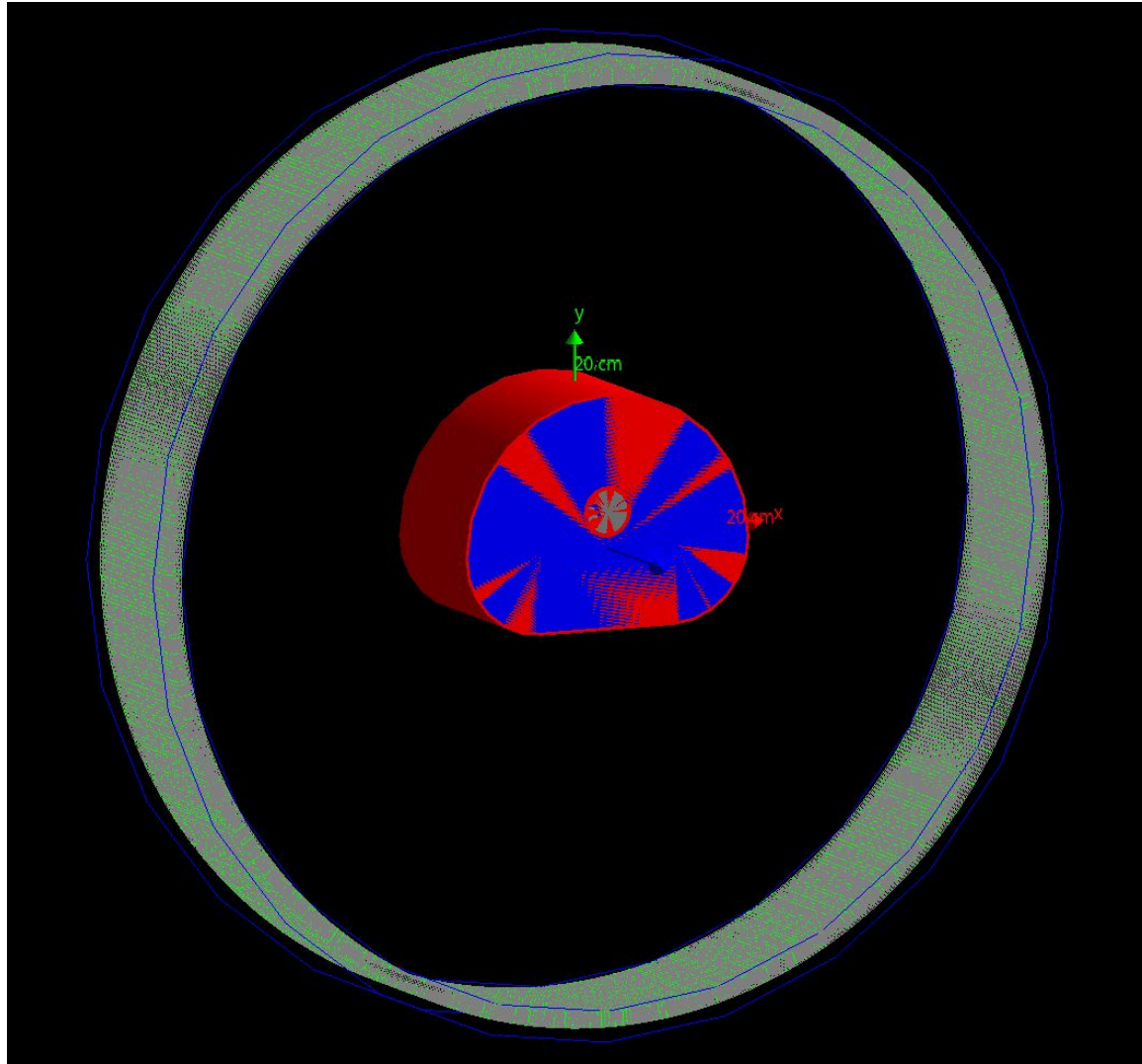
- A repetition of 40 “GATE modules” in z direction
 - Gap of 10 microns between “GATE modules”
 - Total volume 15 mm x 3.76 mm x 150.4 mm

Scanner



- Ring of 751 rsectors, r_{min} 45 cm

Scanner + source



- NEMA IQ phantom (provided by Nikos)

Physics and cuts

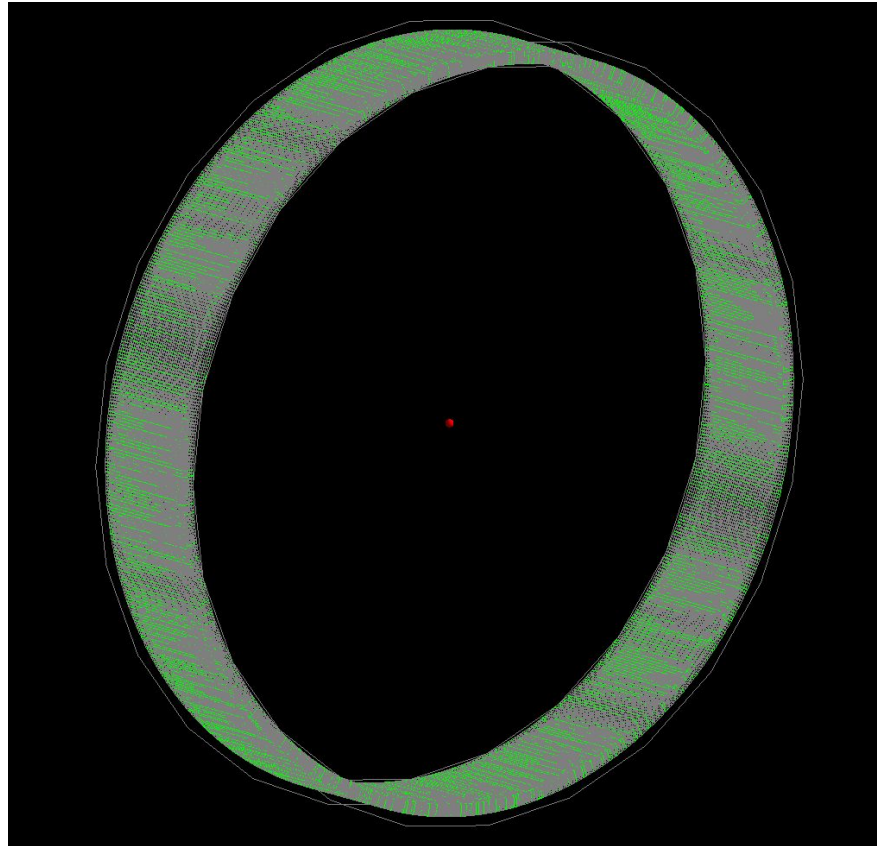
```
/gate/physics/addPhysicsList emstandard_opt3
# /gate/physics/addProcess DecayPhysics
/gate/physics/addProcess PositronAnnihilation e+
/gate/physics/addProcess RadioactiveDecay

/gate/physics/processList Enabled
/gate/physics/processList Initialized

#
#      C U T S
#
# Cuts for particles
/gate/physics/Gamma/SetCutInRegion      world {cut} um
/gate/physics/Electron/SetCutInRegion   world {cut} um
/gate/physics/Positron/SetCutInRegion    world {cut} um
```

- Short production cuts allow sharing of energy between tiles
- Cuts can be defined at run time with command line parameter (see instructions on github)

Test for cuts and energy sharing



- “Phantom” = Plastic sphere, 5 mm radius
- Placed in center of FOV
- Source = sphere, 1 mm radius, center of “phantom”
- 43 MBq ^{18}F e^+ iso source

Production cuts

Production cut [μm]	Coincidences (en. > 400 keV)	Fast events [%]	Disk space [GB]	Total CPU time [h]
	<i>For ~2 GATE seconds</i>			
1000	73789	0.689	2.2	8.9
100	64408	15.72	15.2	23.5
75	64780	16.04	16.5	23.5
50	64410	16.15	18	22.7
25	63980	16.81	19	25
10	64075	16.91	20	27.1
5	64533	17.42	20.5	29.5
1	64401	17.08	43	110.1

- Quick test on Ixplus (200 jobs x cut)
- Analysis on GATE **Hits**:
 - Coincidence = same eventID, more than 400 KeV in 2 “GATE modules” (our crystals)
 - Fast events = both crystals with > 10 keV deposited in the Plastic material
- Results are ok for cuts < **25-10** micron

Fast and slow coincidences

- Fixing production cuts at 25 microns
- Definitions:
 - Fastest = > 10 keV deposited in Plastic in both crystals involved in coincidence
 - Fast = > 10 keV deposited in Plastic in just 1 crystal involved
 - Standard = < 10 keV deposited in Plastic in both crystals involved in coincidence
- Percentages:
 - Fastest = 16.81%
 - Fast = 48.34%
 - Standard = 34.85%

Digitizer

```
/gate/digitizer/Singles/insert adder
/gate/digitizer/Singles/insert readout
/gate/digitizer/Singles/readout/setPolicy TakeEnergyWinner
/gate/digitizer/Singles/readout/setDepth 2

/gate/digitizer/Singles/insert thresholder
/gate/digitizer/Singles/thresholder/setThreshold 300. keV
/gate/digitizer/Singles/insert upholder
/gate/digitizer/Singles/upholder/setUphold 700. keV

/gate/digitizer/name Coincidences
/gate/digitizer/insert coincidenceSorter
/gate/digitizer/Coincidences/setWindow 0.1 ns
/gate/digitizer/Coincidences/minSectorDifference 1

/gate/digitizer/Coincidences/MultiplesPolicy takeAllGoods
```

- Readout depth defined at module level (it's out crystal element)
- What is a suitable coincidence window?